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## AMENDMENTS TO THE SPECIFICATION

Please amend the title of the application appearing on page 1 of the specification as follows:

LARGE TILT ANGLE MEM MICROELECTROMECHANICAL SYSTEM FOR  
TILTING A PLATFORM

Please amend the paragraph beginning on page 9 at line 1 of the specification as follows:

FIGS. 5A-C5A, 5B and 5C show plan and side views of one embodiment of a segmented torsional spring compliant member in accordance with the present invention;

Please amend the paragraph beginning on page 9 at line 6 of the specification as follows:

FIG. 7 shows a schematic plan view of another embodiment of a MEM system in accordance with the present invention wherein the platform is not attached to the substrate.